

Evaluation of lateral depletion in the edge region and evaluation of punch-through-protection in the strip ends before and after irradiation

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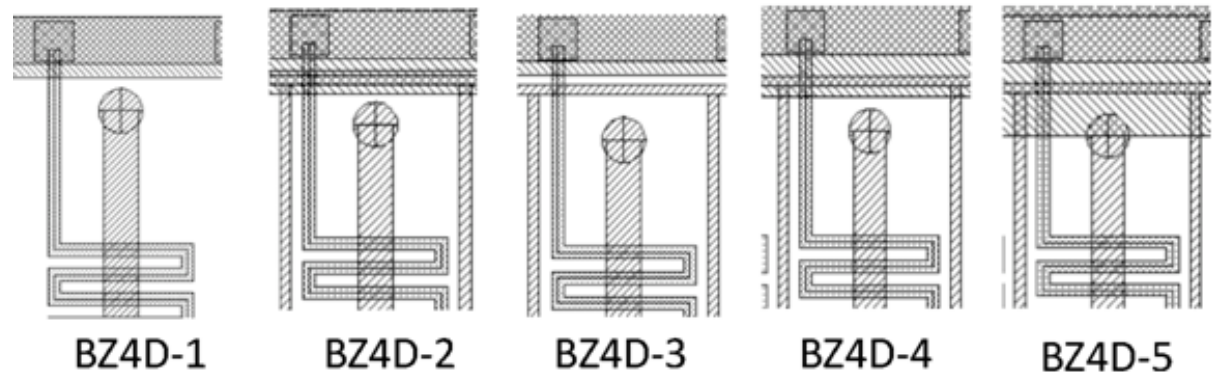
Proton irradiation

- Irradiation
 - 70 GeV protons irradiated at CYRIC
 - $5.7e12, 1.1e13, 1.2e14, 1.2e15$ n_{eq}/cm^2
- Samples
 - fabricated by Hamamatsu K.K.
 - Punch Trough Protection
 - miniature strip sensor (1cm x 1cm)
 - Slim Edge
 - diode (4mm x 4mm)
 - Multi Guard
 - diode (4mm x 4mm)

New Punch Through Protection

Samples

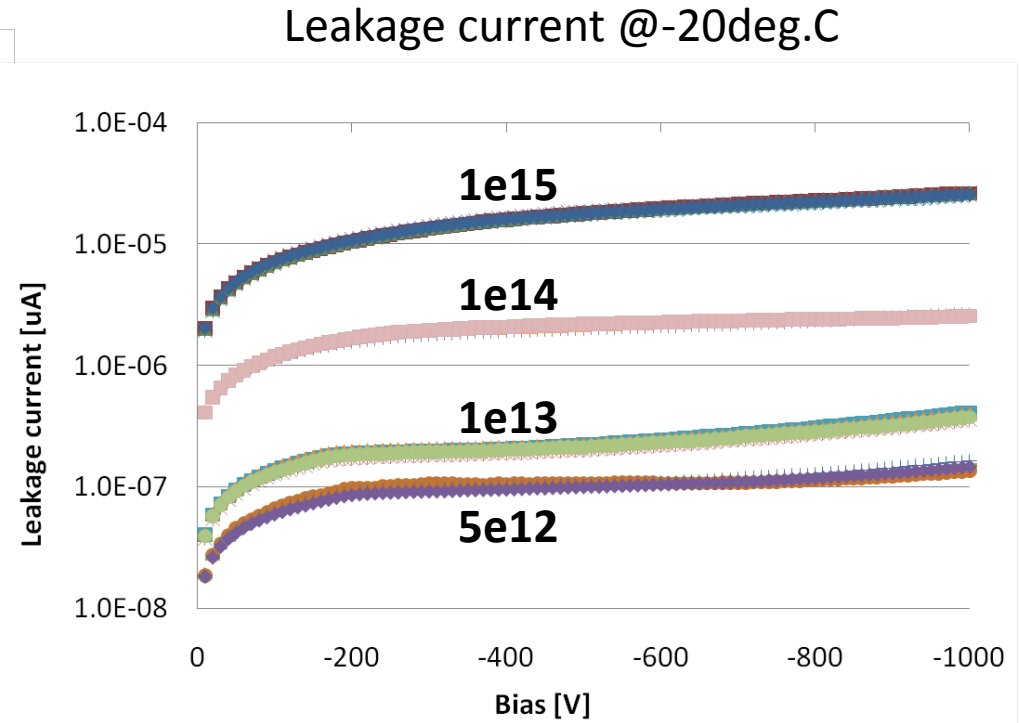
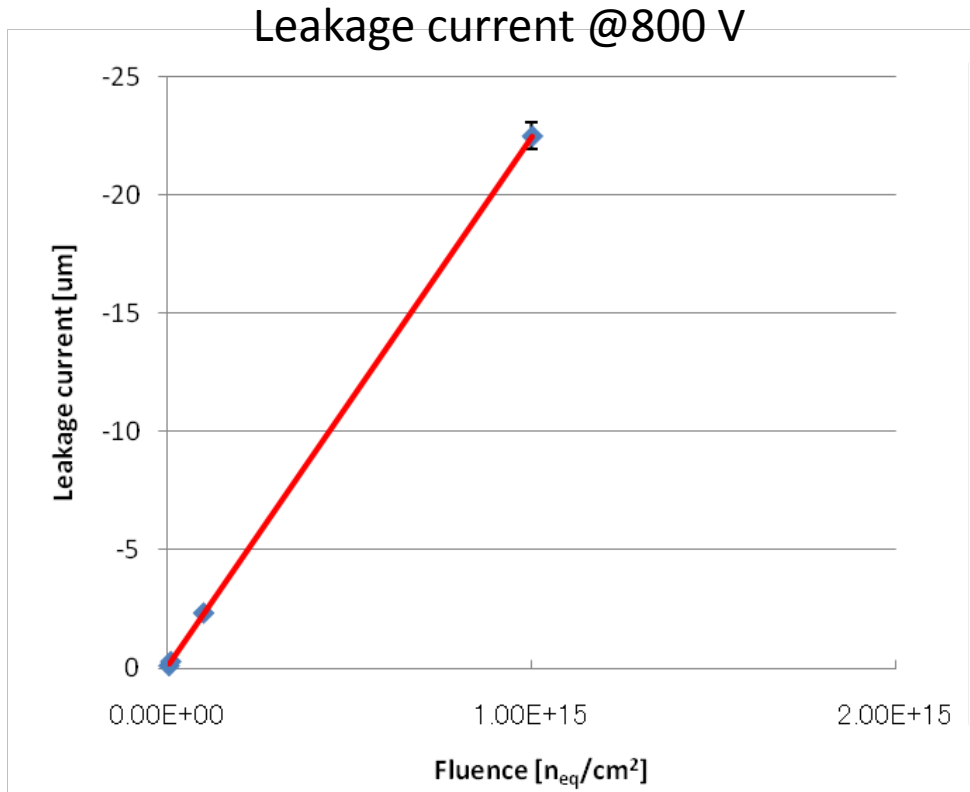
- p-sub (W11,W12,W13,W14)
- Bias ring Al extension
- BZ4D
 - 1: No p-stop
 - 2: Up to p-stop
 - 3: No extension
 - 4: Over p-stop
 - 5: Full extension



Measurement

- before annealing (after anneal is preliminary), temperature at -20deg.C
- IV measurement
 - measure the leakage current
- CV measurement
 - measure the body capacitance
 - evaluate the Full Depletion Voltage
- PTP measurement
 - measure the resistance applying voltage between bias ring and DC pad (strip implant)
 - $V_{bias} = -300$ V constant

Leakage current



$$\Delta I = \alpha \times \Phi \times V$$

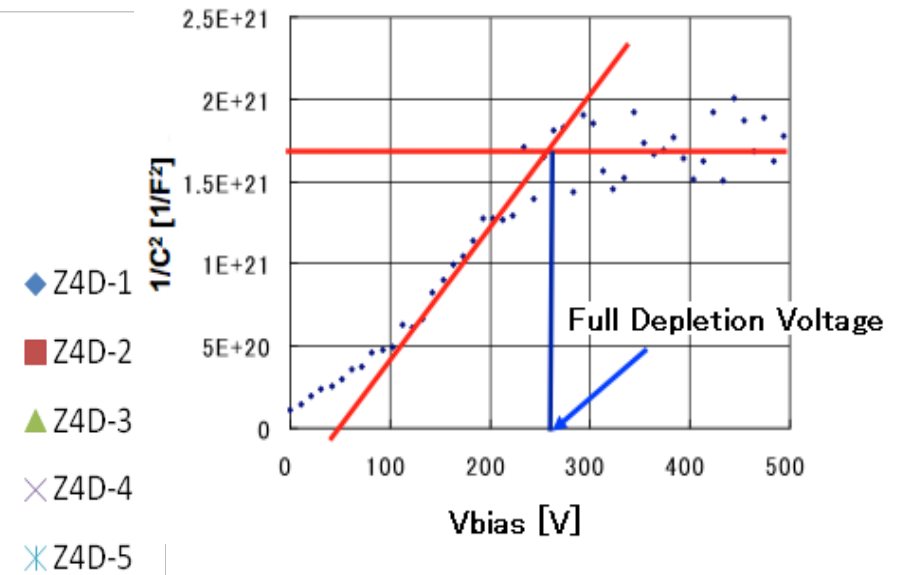
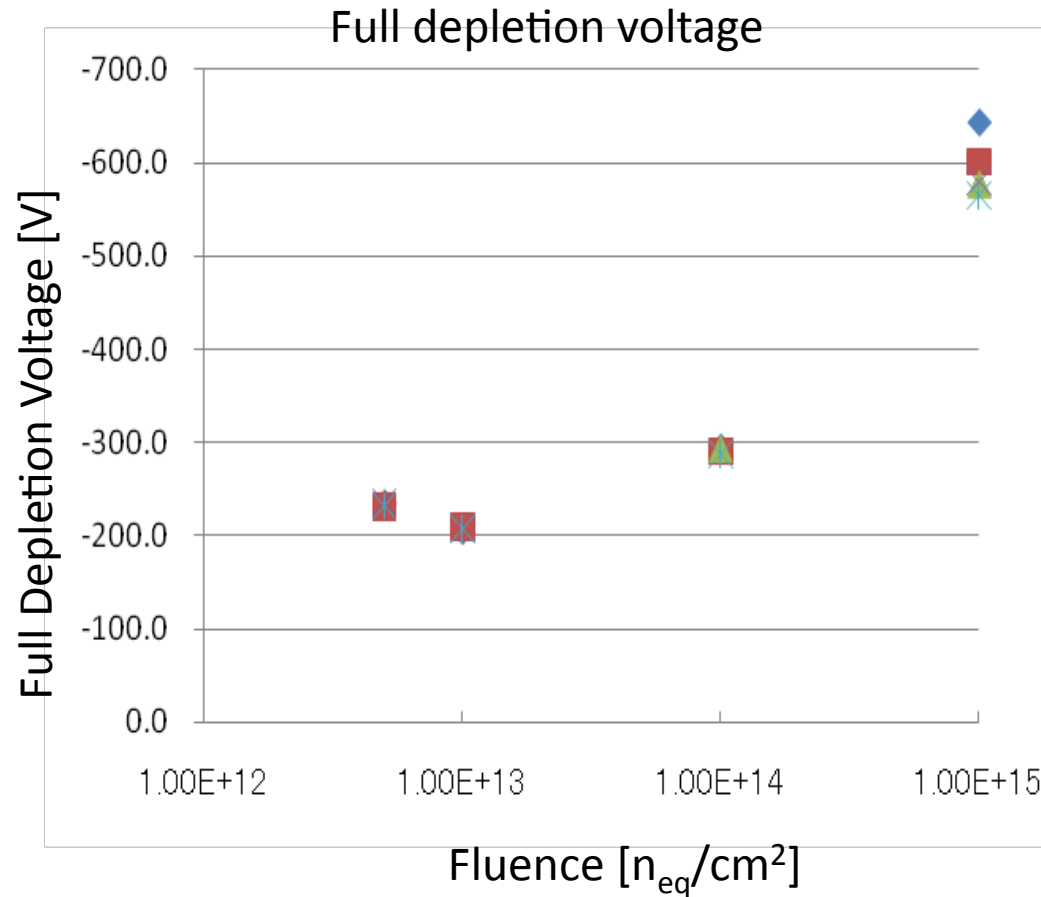
No onset of microdischarge up to 1000 V

ΔI = current, α = damage constant, Φ = fluence, V = sample volume

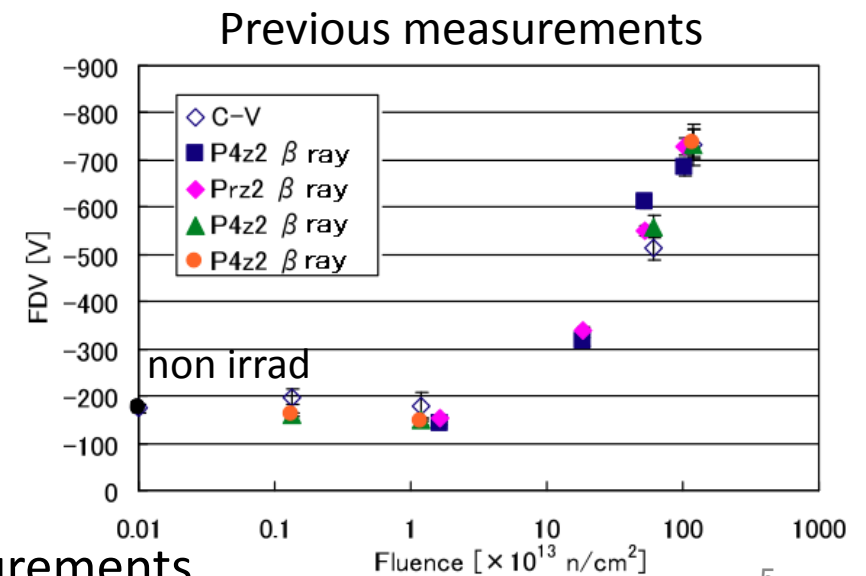
damage constant = 4.1×10^{-17} A/m

=>consistent with known value 3.99×10^{-17} A/m

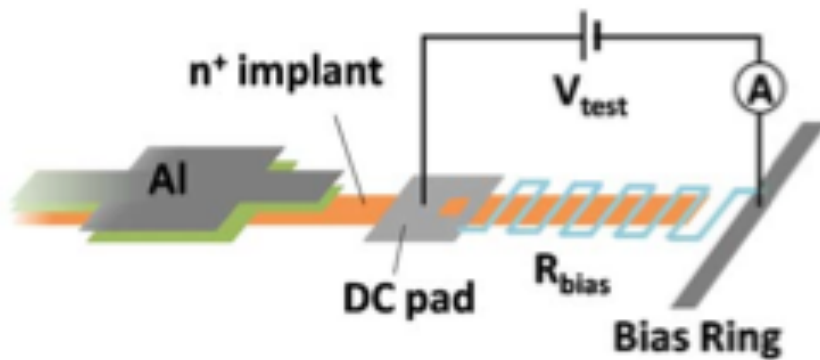
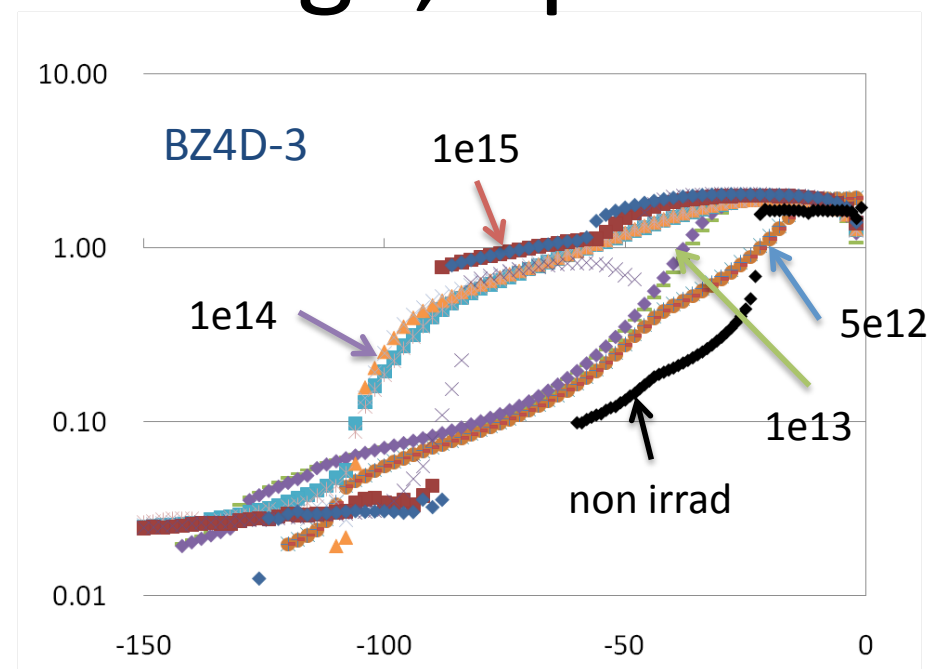
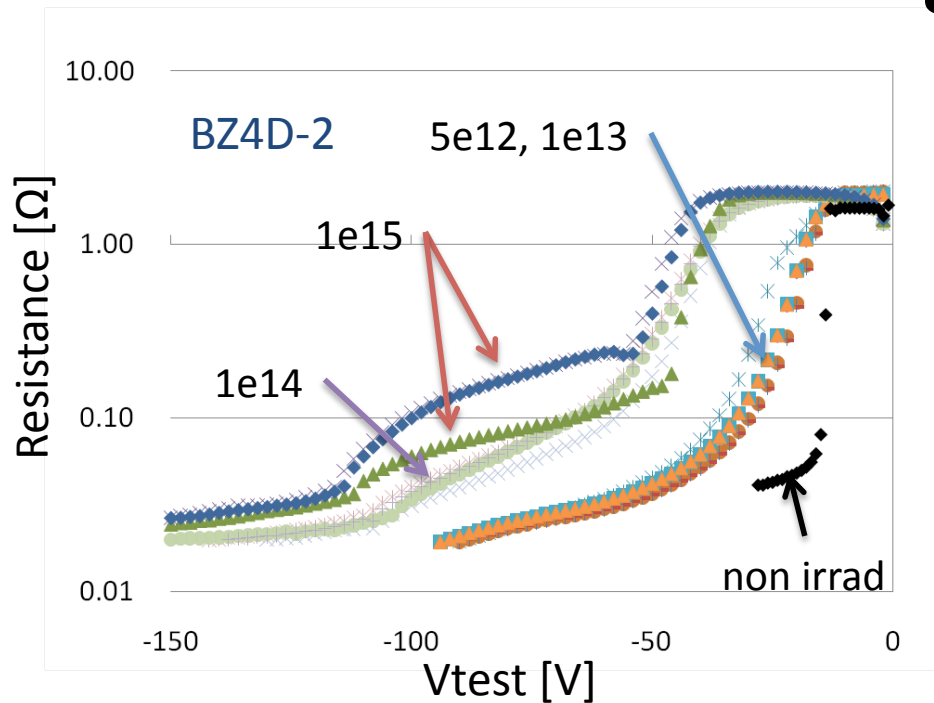
Full Depletion Voltage



- $1/C^2$ is linearly dependent on Vbias
- after full depletion, $1/C^2$ is constant
- FDV reach -600 V at $10^{15} n/cm^2$
- => FDV is consistent with previous measurements

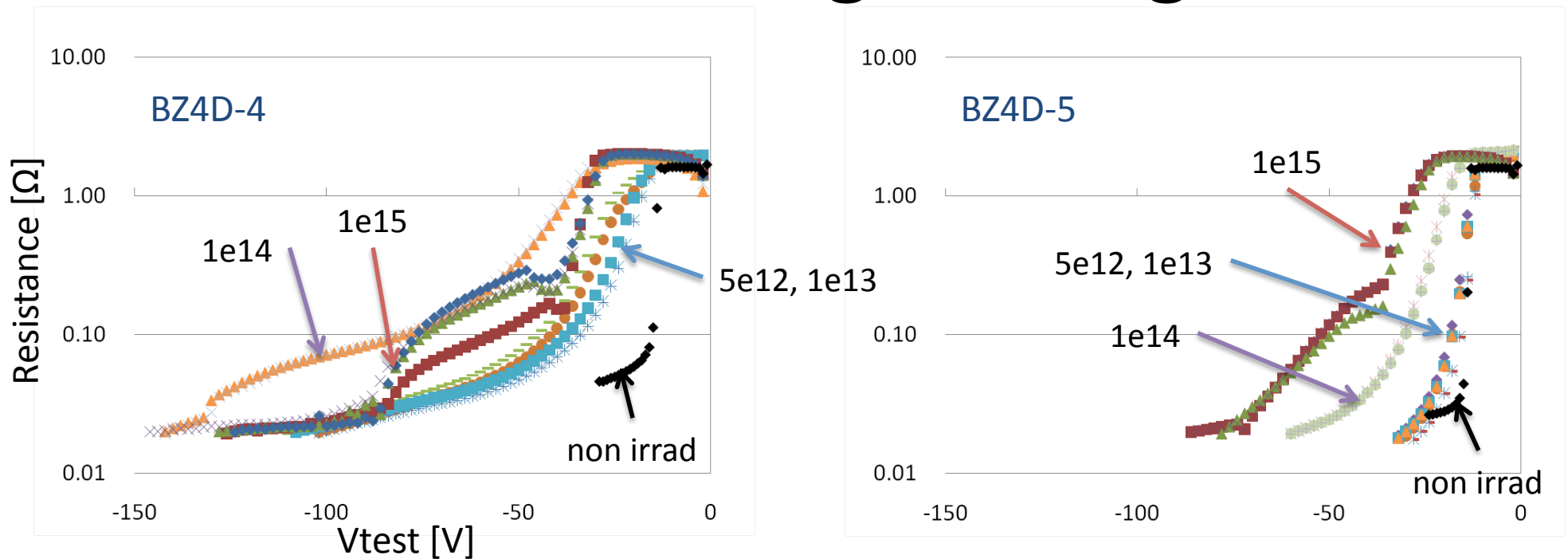


Punch Through Voltage, V_{pt}



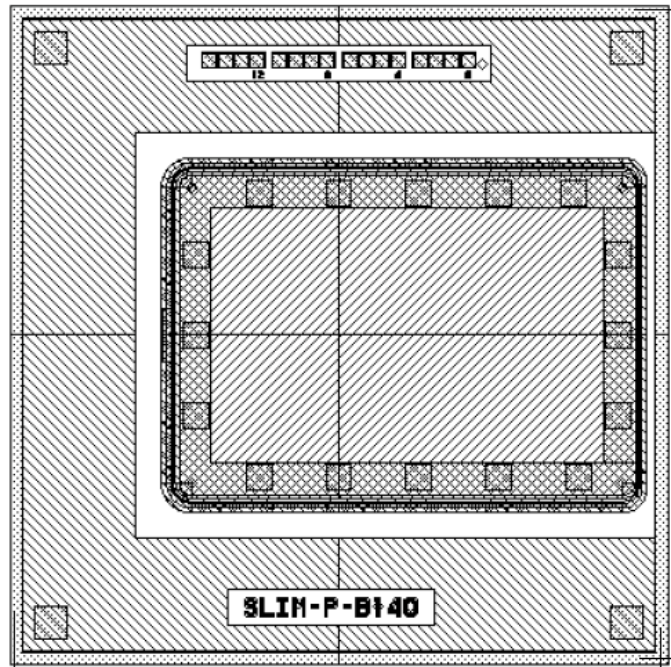
- Apply V_{test} up to -150 V
- measure resistance between bias ring and DC pad
- Onset voltage, V_{pt} , increases as fluence increases
- BZ4D-2 is better than -3 caused by extended Al
 - Lower V_{pt}
 - Sharper cutoff
 - Lower saturation resistance

Punch Through Voltage



- Punch through voltage depend on Al extension
- BZ4D-5 is the best amongst the types
 - Saturation $V_{pt} < 100$ V and resistance ≤ 20 k Ω
 - ~ 5 mA! per strip ($\equiv \sim 10$ kMIPS/25ns/strip)
 - It would protect the AC coupling insulator of breakdown ~ 120 -150 V

Slim Edge Study



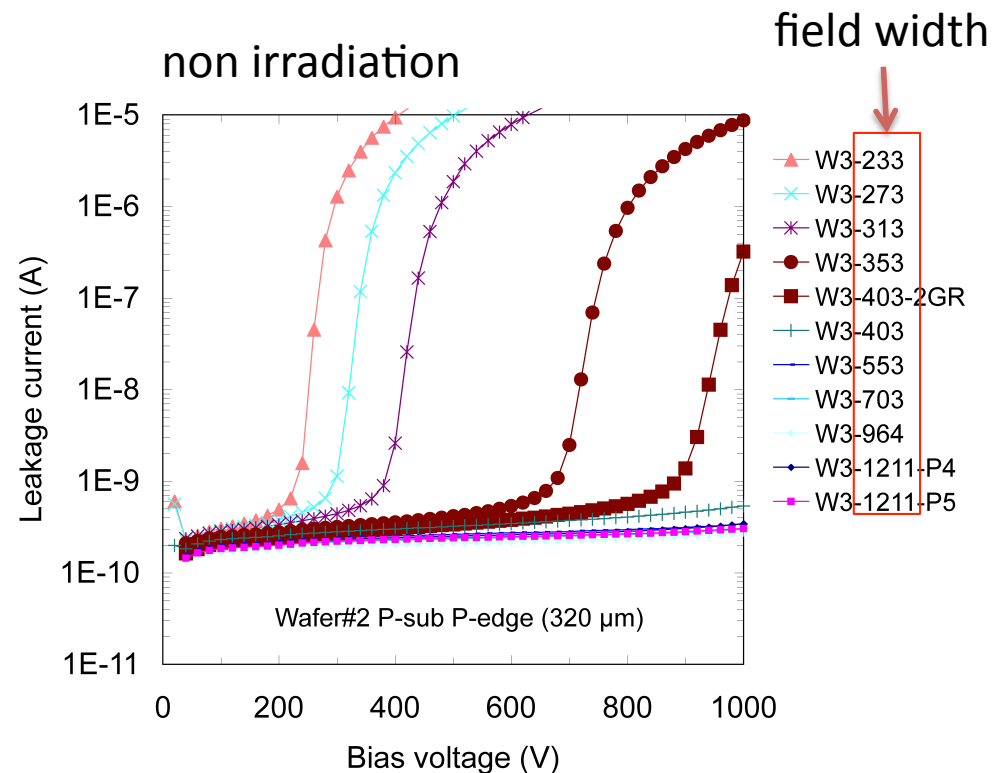
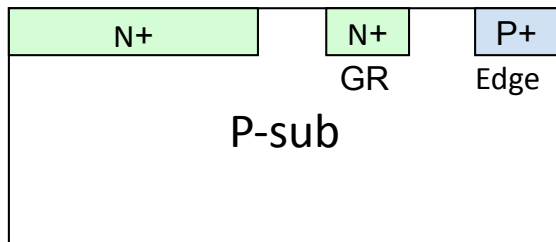
- Only in one side, the distance-to-edge is varied from 80 to 1000 μm
- Our goal is to deduce the required width for operating the silicon sensor up to 1000 V

Samples

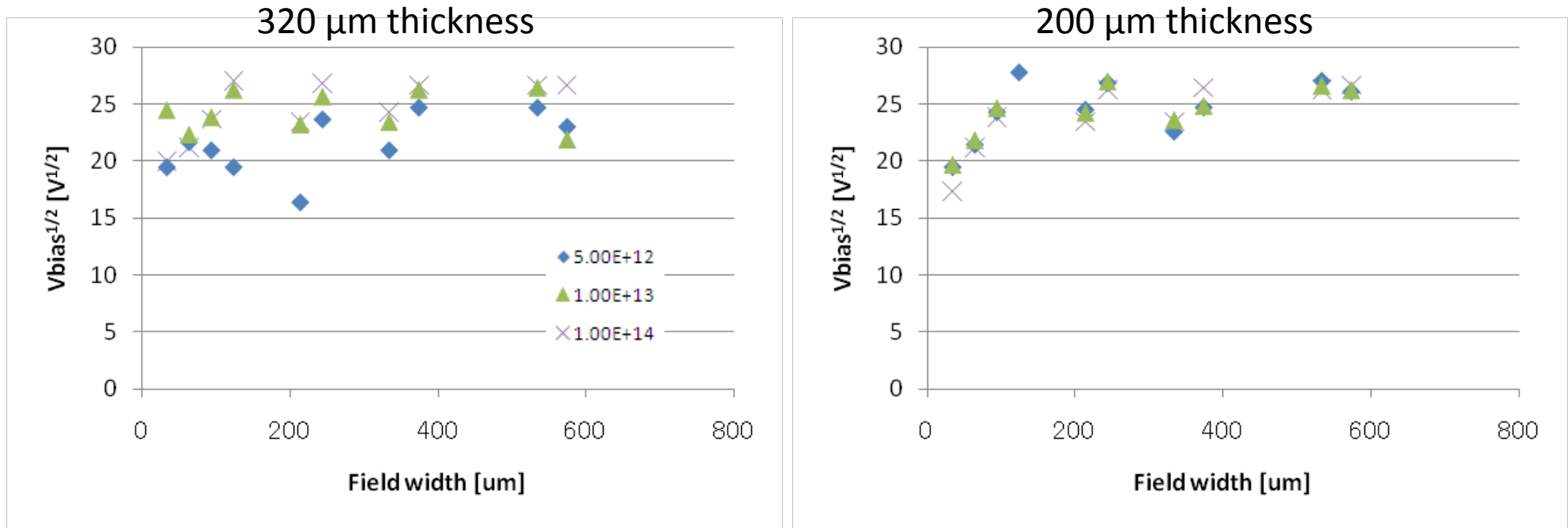
- p-sub : preliminary
 - n-sub : 320 and 200 μm thickness, p-edge or n-edge
 - Fluence : 5.7e12, 1.1e13, 1.2e14 n/cm²
 - Annealed: at 60deg.C for 80min
- “Field width” is the width without implantation between the edge implant and the bias ring implant
 - 34, 64, 94, 124, 214, 244, 334, 374, 534, 574 μm

Slim Edge Study – Lateral Depletion

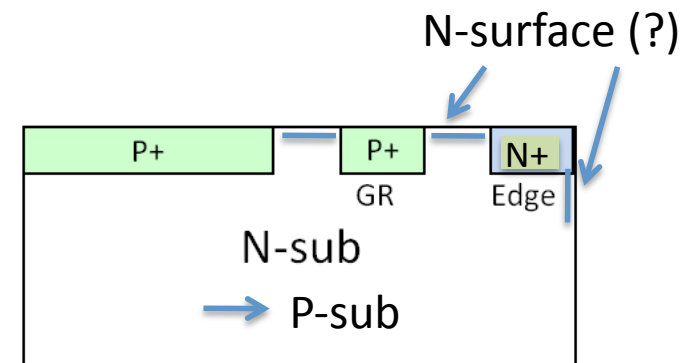
- Evaluating the relation between the edge space and the bias voltage to hold
 - Lateral depletion along the surface
- onset of microdischarge increase as field width is wide



Slim edge N-sub N-edge

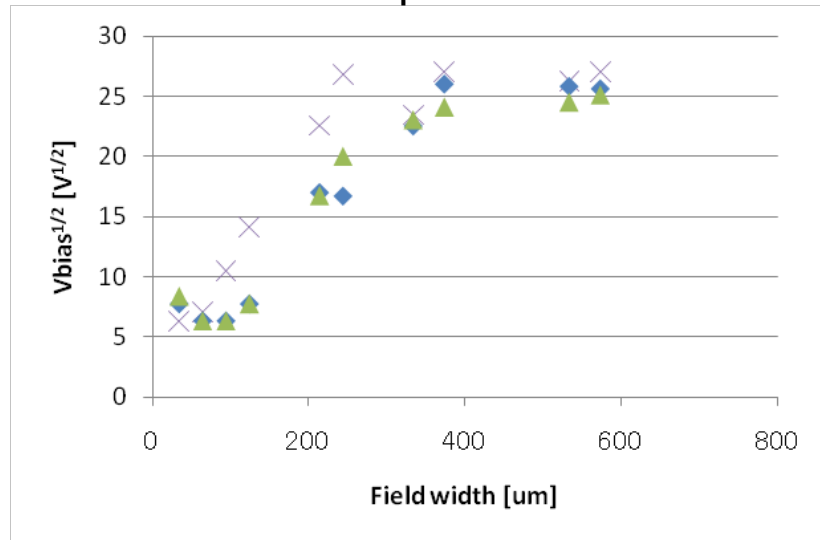


- Note that the substrate type may have changed to p-type by irradiation over 10^{14} n/cm²
- No difference in the fluences
 - Surface is N-type even with $1\text{e}14$...
 - Thus, no p-n junction at the edge
- All show good bias voltage tolerance
 - Too good for the study
 - Although the onset voltages were all ~ 600 V

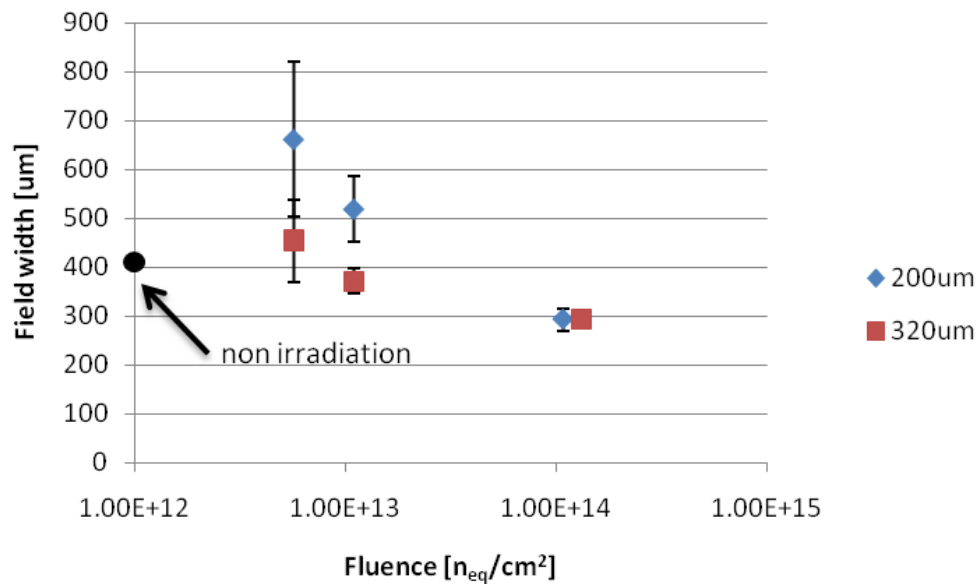
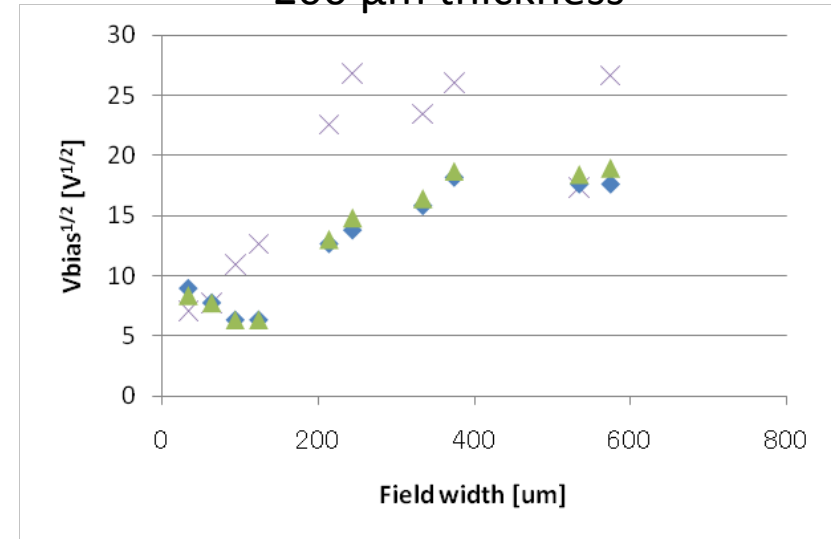


Slim edge N-sub P-edge

320 μm thickness

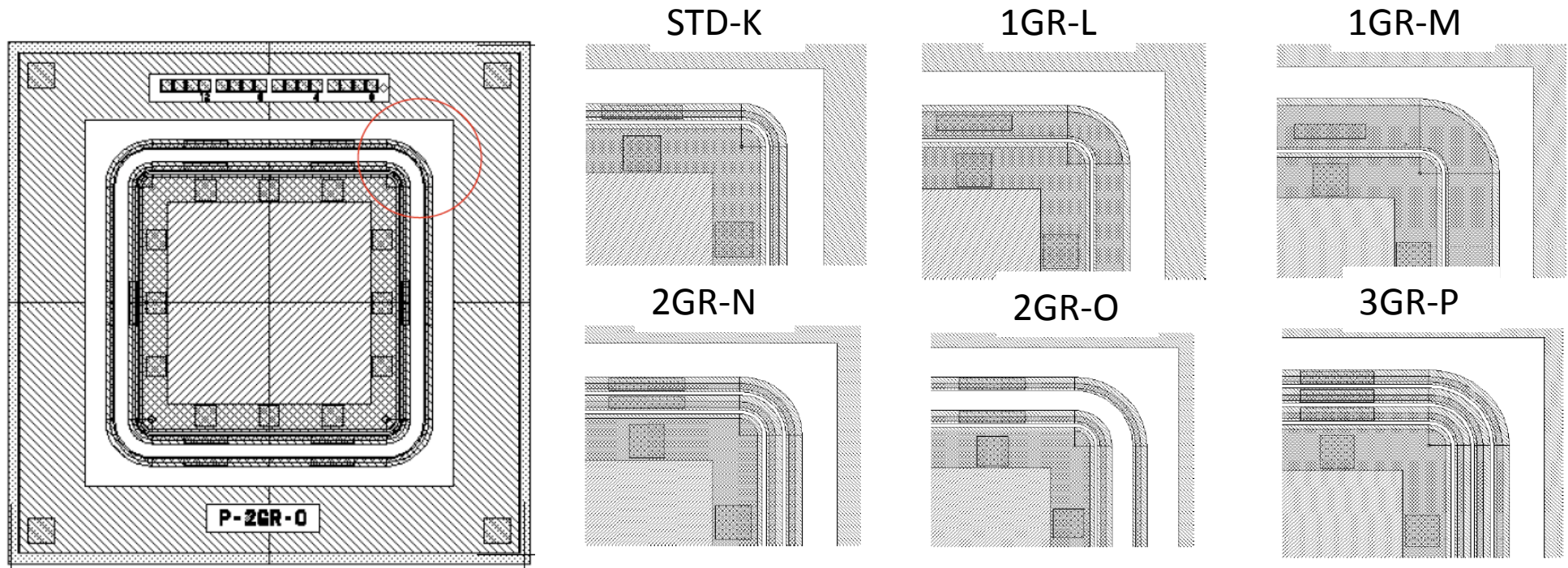


200 μm thickness



- The substrate type changes to p-type by irradiation over 10^{14} n/cm^2
 - Surface is still N-type
 - p-n junction at the edge
- Onset voltages were ~ 600 V or lower
 - then, extrapolate to 1000 V
- The field width holding 1000 V (?)
 - => ~ 400 μm

Multi guard study

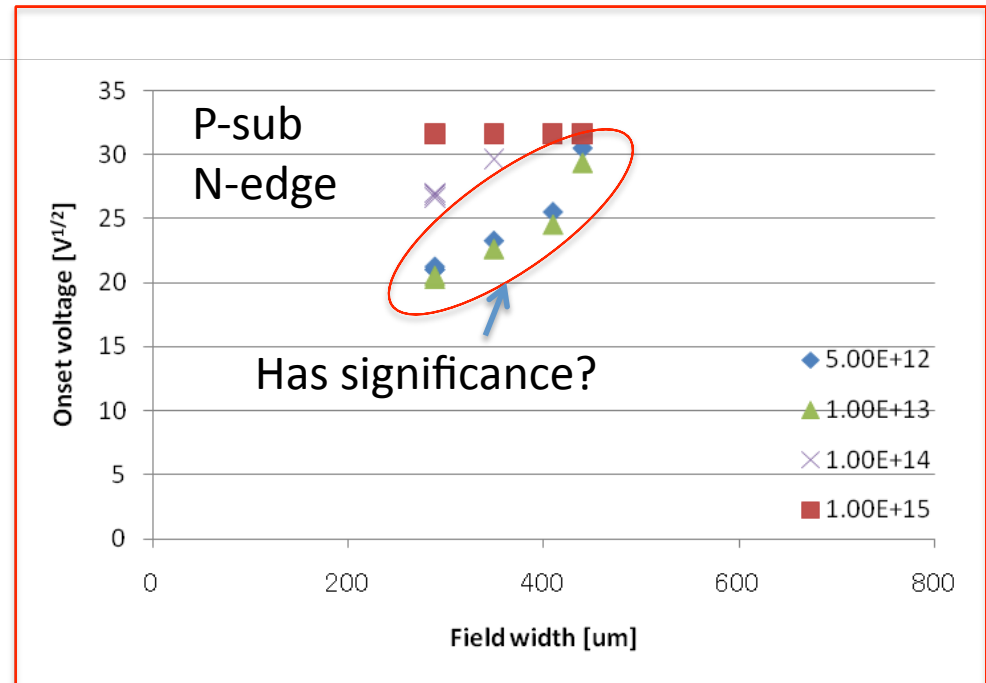
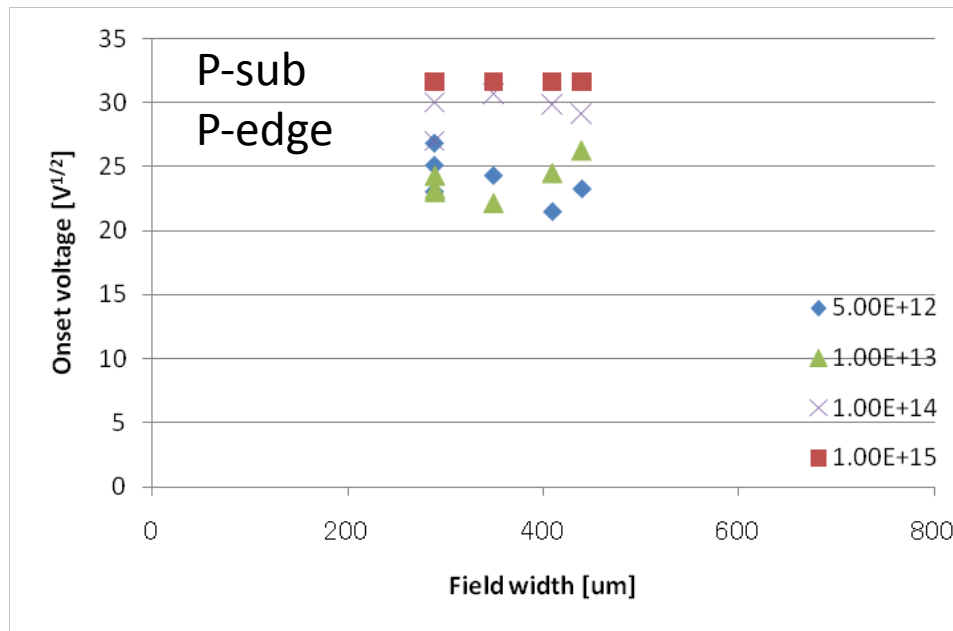


- In order to investigate whether the number of guard rings will help to reduce the edge distance

Samples

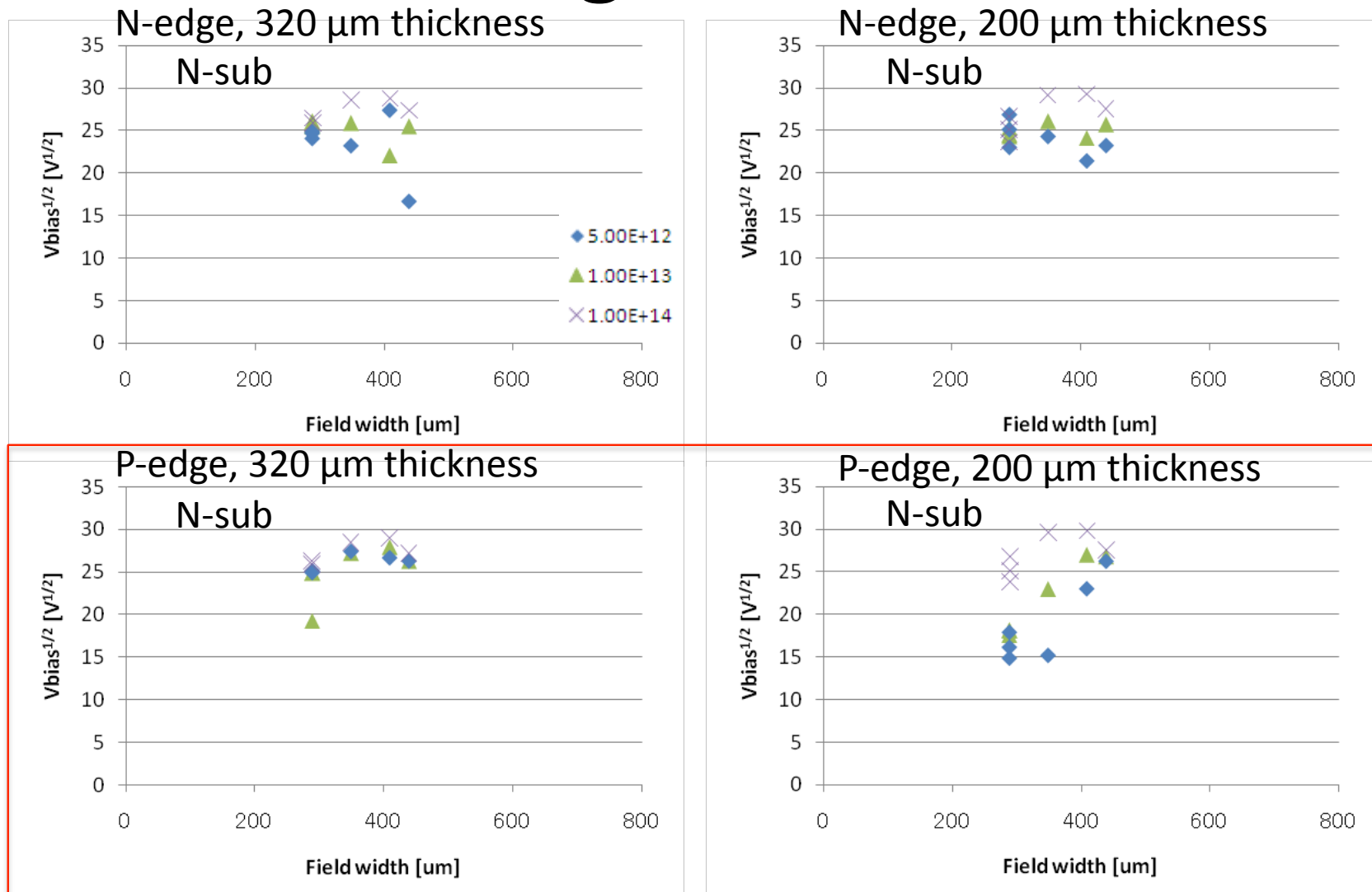
- Field width :
 - STD-K = 1GR-L = 1GR-M (289 μm), 2GR-N (349 μm), 3GR-P (409 μm), 2GR-O (439 μm)
 - Watch the number of guard rings in the sequence of “Field width”
- p-sub : 320 μm thickness, p-edge/n-edge
- n-sub : 320 and 200 μm thickness, p-edge/n-edge
- Fluence : 5.7e12, 1.1e13, 1.2e14, 1e15 n/cm², Annealed at 60deg.C for 80 min.

Multi guard P-sub 320 μm thickness



- Evaluation of the onset voltages of microdischarge by IV measurement
- The onset voltage increases as the fluence increases
 - irrespectively of the variation of the guard rings
- P-sub/P-edge: insensitive, and the onset voltage of microdischarge is little different on the number of guard rings
- P-sub/N-edge: sensitive to the reach of the depletion to the edge
 - 3 guard rings is no better than 2 guard rings

Multi guard N-sub



- Little dependence on the guard rings
- Thinner may require wider field width

Summary

- PTP
 - BZ4D-5 (with full coverage) is the best among the samples, has potentiality to protect the AC coupling insulator, even after irradiation to $1 \times 10^{15} n_{eq}/cm^2$
- Slim edge
 - N-sub/N-edge is still insensitive to the reach of the depletion after $1 \times 10^{14} n_{eq}/cm^2$
 - N-sub or P-sub may require $\geq 400 \mu m$ field width to hold 1000 V
 - Thinner may require wider width
- Multi guard
 - Little fundamental difference on the number of guard rings in order to reduce the width of the edge, and the onset voltage of the microdischarge